

Notice of References Cited

Application/Control No.

09/921,786

Applicant(s)/Patent Under
Reexamination
DREVILLON ET AL.

Examiner

Carlos Ortiz-Rodriguez

Art Unit

2125

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U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-5,042,951 ✓	08-1991	Gold et al.	356/369
	B	US-5,223,356 ✓	06-1993	Kumar et al.	430/1
	C	US-5,494,697 ✓	02-1996	Blayo et al.	427/10
	D	US-6,081,334 ✓	06-2000	Grimbergen et al.	356/499
	E	US-6,504,608 ✓	01-2003	Hallmeyer et al.	356/369
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N	EP0653621A1 ✓	05-1995	DE FR GB	Blayo, Nadine	GO1N 21/21
	O					
	P					
	Q					
	R					
	S					
	T					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)			
	U	Kildemo et al., "Real time control of the growth of silicon alloy multilayers by multiwavelength ellipsometry"; Thin Solid Films, Dec. 1996; Vol. 290-291; pages 46-50. ✓			
	V	M. Kildemo et al., "A direct robust feedback method for growth control of optical coatings by multiwavelength ellipsometry"; Thin Solid Films, Dec. 1998; Vol. 313-314; pages 484-489. ✓			
	W				
	X				

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.